

ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

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Title of Invention

METHOD FOR REACTIVE ION ETCH PROCESSING OF A
DUAL DAMASCENE STRUCTURE

Application Number : 10/709,630

Confirmation Number:

First Named Applicant: William America

Attorney Docket Number: FIS920040053US1

Art Unit: 2825

Examiner: B. KESHAVAN

Search string: (6479391 or 6514852 or 6573176 or 6576482).pn

US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
BK	1	6479391	2002-11-12	Morrow et al	—	—	—
BK	2	6514852	2003-02-04	Usami	—	—	—
BK	3	6573176	2003-06-03	Hong	—	—	—
BK	4	6576482	2003-06-10	Aggarwal et al	—	—	—

Signature

B. Keshavan

11/22/2004

Examiner Name	Date
B. KESHAVAN	11/22/2004

